FAPG150 Fully-automatic Probe Station

PEGASUS FAPG150 is develpoed for testing components such as DIODE, MOSFET and IGBT wafers. PEGASUS FAPG150 is a probe station with double-sided automatic probe structure. A robot arm automatically picks up a wafer to pre-aligner and to the probing position. The circular chuck plate provides a stable and fast test environment. For different applications, it is possible to set the optimal probing speed and probe mark. Customized designs are also available on request.

Features

- Simple operation interface and joystick design
- Wafer mapping creation and editing functions
- Easy-to-use English Windows user interface
- Different product profiles can be created
- Automatic wafer alignment and search for the initial die
- Easy-to-maintain modular electronic control structure
- High-precision drive motor provides a stable and quiet operating environment
- Two cassettes can be placed at the same time
- Pre-aligner for wafer alignment
- Standard TTL/RS232 communication interface for variety of testers
- Excellent probing speed and probe marks
- Customized designs available
- Selectable 4" or 6" chuck plate

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Specifications

X/Y axis

- Architecture: High-precision circulating ball screw
- Travel: 285mm × 250mm
- Resolution: 0.5 μm
- Accuracy: ⩽±7 μm /203mm
- Repeatability: ⩽±4 μm/203mm

Z axis

- Travel: 10mm
- Resolution: 1 μm
- Accuracy: ≦±4 μm
- Repeatability: ≦±4 μm

Theta axis

- Travel: ±10°
- Resolution: 0.001°

Chuck plate

- Material: PEEK
- Wafer size: 4” ~ 8”
- Hot chuck optional

CCD Wafer level adjustment

- Designed for your chip size
- Standard: 1/3” 1024X768 CCD
- 0.5X lens(ROI: 9.6mm X 7.2mm)

Microscope

- Three-eye microscope
- LED ring lamp
- Magnification: X0.67 ~ X4.5
- Eyepiece: X10 or X20

Dimensions

- 950(D) × 1360(W) × 1730(H) mm

(Excludes display and signal tower)

Weight

- 550Kg((Excludes tester))

Vacuum

- 4-6Kgf/cm²

Air pressure

- 0.5MPa